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# Contents – Volume II

<b>1</b>	<b>Higher Harmonics in Dynamic Atomic Force Microscopy</b>	
	<i>Robert W. Stark, Martin Stark</i> . . . . .	1
1.1	Introduction . . . . .	1
1.2	Multimodal Model of the Microcantilever . . . . .	4
1.2.1	Overview . . . . .	4
1.2.2	Modal Analysis . . . . .	5
1.2.3	Tip–Sample Interaction . . . . .	7
1.2.4	State Space Formulation . . . . .	9
1.2.5	Dynamics: Linearized Tip–Sample Interaction . . . . .	11
1.2.6	Poles and Zeros . . . . .	13
1.2.7	Dynamics: Nonlinear Interaction . . . . .	16
1.2.8	Optical Readout . . . . .	20
1.3	Higher Harmonic Imaging . . . . .	23
1.4	Spectroscopy: Distinguishing Two Polymers . . . . .	27
1.4.1	Overview . . . . .	27
1.4.2	Experimental Details . . . . .	28
1.4.3	Signal Analysis . . . . .	28
1.5	Outlook . . . . .	33
	References . . . . .	33
<b>2</b>	<b>Atomic Force Acoustic Microscopy</b>	
	<i>Ute Rabe</i> . . . . .	37
2.1	Introduction . . . . .	38
2.1.1	Near-field Acoustic Microscopy . . . . .	39
2.1.2	Scanning Probe Techniques and Nanoindentation . . . . .	40
2.1.3	Vibration Modes of AFM Cantilevers . . . . .	41
2.2	Linear Contact-resonance Spectroscopy Using Flexural Modes . . . . .	42
2.2.1	Flexural Vibrations of Clamped-free Beams . . . . .	44
2.2.2	The Point-mass Model . . . . .	47
2.2.3	Experiments with Clamped-free Beams . . . . .	48

2.3	Contact Forces as Linear Springs and Dashpots . . . . .	51
2.4	Characteristic Equation of the Surface-coupled Beam . . . . .	55
2.4.1	Discussion of the Characteristic Equation . . . . .	58
2.4.2	Influence of an Additional Mass . . . . .	61
2.4.3	Roots of the Characteristic Equation with Damping . . . . .	63
2.5	Forced Vibration . . . . .	64
2.6	Imaging and Contrast Inversion . . . . .	70
2.7	Sensitivity of the Flexural Modes . . . . .	73
2.8	Quantitative Evaluation . . . . .	76
2.8.1	Experiments for Quantitative Evaluation . . . . .	78
2.9	Nonlinear Forces . . . . .	82
2.10	Conclusions . . . . .	83
A	Appendix . . . . .	84
A.1	Definitions . . . . .	84
A.2	UAFM-mode . . . . .	85
A.3	AFAM-mode . . . . .	86
	References . . . . .	88

### **3 Scanning Ion Conductance Microscopy**

*Tilman E. Schäffer, Boris Anczykowski, Harald Fuchs . . . . .* 91

3.1	Introduction . . . . .	91
3.2	Fundamental Principles . . . . .	92
3.2.1	Basic Setup . . . . .	92
3.2.2	Nanopipettes . . . . .	95
3.2.3	Electrodes . . . . .	96
3.3	Ion Currents Through Nanopipettes . . . . .	97
3.3.1	Background Theory . . . . .	97
3.3.2	Simple Analytical Model . . . . .	97
3.3.3	Finite Element Modeling . . . . .	99
3.3.4	Experimental Current-Distance Curves . . . . .	101
3.3.5	Imaging with Ion Current Feedback . . . . .	102
3.4	Advanced Techniques . . . . .	103
3.4.1	Modulation Methods . . . . .	104
3.4.2	Applications in Bioscience . . . . .	106
3.5	Combination with Other Scanning Techniques . . . . .	107
3.5.1	Combination with Atomic Force Microscopy . . . . .	108
3.5.2	Application in Material Science . . . . .	108
3.5.3	Combination with Shear Force Microscopy . . . . .	111

3.5.4	Application in Bioscience . . . . .	114
3.6	Outlook . . . . .	115
	References . . . . .	116

#### **4 Spin-Polarized Scanning Tunneling Microscopy**

	<i>Wulf Wulfhekel, Uta Schlickum, Jürgen Kirschner</i> . . . . .	121
4.1	Introduction . . . . .	121
4.1.1	The Resolution Problem in Magnetic Imaging . . . . .	121
4.1.2	Magnetism and Spin . . . . .	122
4.1.3	The Tunneling Magnetoresistance Effect . . . . .	122
4.2	The Principle of Spin-polarized Scanning Tunneling Microscopy . . . . .	124
4.2.1	The Constant Current Mode . . . . .	125
4.2.2	The Spectroscopic Mode . . . . .	125
4.2.3	Differential Magnetic Imaging Mode . . . . .	126
4.3	Experimental Set-up . . . . .	127
4.4	Ferromagnetic Domains and Domain Walls . . . . .	128
4.4.1	Ultra-sharp Domain Walls in Co(0001) . . . . .	129
4.4.2	Asymmetric Néel Caps in Fe(001) . . . . .	131
4.5	Antiferromagnets in Contact with Ferromagnets . . . . .	133
4.5.1	Mn on Fe(001) and Topologically Induced Frustrations . . . . .	133
4.5.2	The Layered Antiferromagnet Cr on Fe(001) . . . . .	136
4.6	Bulk Versus Surface: Which Electronic States Cause the Spin Contrast? . . . . .	137
4.6.1	Voltage Dependence of the TMR Effect in Co(0001) . . . . .	137
4.6.2	Voltage Dependence of the TMR Effect in Cr/Fe(001) . . . . .	139
4.7	Conclusion . . . . .	140
	References . . . . .	140

#### **5 Dynamic Force Microscopy and Spectroscopy**

	<i>Ferry Kienberger, Hermann Gruber, Peter Hinterdorfer</i> . . . . .	143
5.1	Introduction . . . . .	144
5.2	Scanning Probe Microscopy . . . . .	145
5.3	Dynamic Force Microscopy Imaging . . . . .	146
5.4	Force Spectroscopy . . . . .	149
5.4.1	Principles . . . . .	149
5.4.2	Theory . . . . .	151
5.4.3	Applications . . . . .	153

5.5	Combined Imaging and Spectroscopy . . . . .	158
5.6	Concluding Remarks . . . . .	161
	References . . . . .	161

## **6 Sensor Technology for Scanning Probe Microscopy and New Applications**

*Egbert Oesterschulze, Leon Abelmann, Arnout van den Bos,  
Rainer Kassing, Nicole Lawrence, Gunther Wittstock,  
Christiane Ziegler . . . . .*

165

6.1	Introductory Remarks . . . . .	165
6.2	Material Aspects of Probe Fabrication . . . . .	166
6.2.1	Mechanical Properties of Cantilever Probes . . . . .	167
6.3	Scanning Near-Field Optical Microscopy . . . . .	174
6.3.1	Principle of Near-Field Optics . . . . .	174
6.3.2	Probes for Scanning Near-Field Optical Microscopy (SNOM) . . . . .	175
6.4	Probes for Ultrafast Scanning Probe Microscopy . . . . .	179
6.4.1	Improved Sampling Technique . . . . .	181
6.5	Functionalized Tips . . . . .	182
6.5.1	Tip Modification . . . . .	182
6.5.2	Applications . . . . .	183
6.6	Scanning Electrochemical Microscopy . . . . .	186
6.6.1	Principles . . . . .	186
6.6.2	Applications . . . . .	189
6.7	Tips for Magnetic Force Microscopy . . . . .	192
6.7.1	Ideal Tip Shape . . . . .	192
6.7.2	Hand-Made Tips . . . . .	193
6.7.3	Coating AFM Tips . . . . .	194
6.7.4	Tip Planes: The CantiClever Concept . . . . .	195
	References . . . . .	197

## **7 Quantitative Nanomechanical Measurements in Biology**

*Małgorzata Lekka, Andrzej J. Kulik . . . . .*

205

7.1	Stiffness of Biological Samples . . . . .	205
7.1.1	Cell Structure . . . . .	205
7.1.2	Determination of Young's Modulus . . . . .	208
7.1.3	Brief Overview of the Application of AFM to Studies of Living Cells . . . . .	217
7.1.4	Summary . . . . .	222

7.2	Friction Force Microscopy . . . . .	224
7.2.1	Friction and Chemical Force Microscopy . . . . .	225
7.2.2	Applications of FFM/CFM . . . . .	229
7.2.3	Summary . . . . .	236
References	. . . . .	237

## **8 Scanning Microdeformation Microscopy: Subsurface Imaging and Measurement of Elastic Constants at Mesoscopic Scale**

	<i>Pascal Vairac, Bernard Cretin</i> . . . . .	241
8.1	Introduction . . . . .	241
8.2	Review and Physical Background of Near-Field Acoustic Microscopes . . . . .	242
8.2.1	Review of Near-Field Microscopes . . . . .	242
8.2.2	Physical Basis for Near-Field Acoustics and the Scale Effect . . . .	244
8.2.3	Mechanical Approach . . . . .	247
8.2.4	Models of Subsurface Sensing Using Acoustic Waves and Surface Bending . . . . .	252
8.3	Imaging and Measurement with Scanning Microdeformation Microscopy . . . . .	254
8.3.1	Configuration . . . . .	254
8.3.2	Application to Subsurface Imaging . . . . .	256
8.3.3	Characterization of Local Mechanical Constants . . . . .	259
8.4	Specific Application . . . . .	260
8.4.1	Thin Film Measurements . . . . .	260
8.4.2	Shape Memory Alloy . . . . .	264
8.4.3	Viscosimetry . . . . .	267
8.5	Ultimate Metrology: Measurements at the Mechanical Noise Level	274
8.6	Conclusion . . . . .	278
References	. . . . .	279

## **9 Electrostatic Force and Force Gradient Microscopy: Principles, Points of Interest and Application to Characterisation of Semiconductor Materials and Devices**

	<i>Paul Girard, Alexander Nikolaevitch Titkov</i> . . . . .	283
9.1	Introduction . . . . .	285
9.2	Principles . . . . .	285
9.2.1	Basic Relations . . . . .	286
9.2.2	Principles of Surface-voltage Measurements . . . . .	287

9.2.3	Detection of Strong Local Electrical Effect via the “Topographic” Data . . . . .	294
9.2.4	Conclusions . . . . .	296
9.3	Observation and Interpretation . . . . .	297
9.3.1	DC Observations . . . . .	299
9.3.2	$\Omega$ Observations . . . . .	300
9.3.3	$2\Omega$ Observations . . . . .	300
9.3.4	Surface Voltage Observations . . . . .	302
9.3.5	Guidelines for Interpretation . . . . .	302
9.4	Future Opportunities . . . . .	304
9.4.1	Interest in the KFGM Method . . . . .	304
9.4.2	Spatially Resolved Observations . . . . .	309
9.4.3	Another Way to Estimate the Maximum Possible Spatial Resolution . . . . .	311
9.5	Some Applications . . . . .	313
9.5.1	Applications Under Ambient Conditions . . . . .	314
9.5.2	Vacuum or UHV Applications . . . . .	316
9.6	Conclusion . . . . .	316
	References . . . . .	318
<b>10</b>	<b>Polarization-Modulation Techniques in Near-Field Optical Microscopy for Imaging of Polarization Anisotropy in Photonic Nanostructures</b> <i>Pietro Giuseppe Gucciardi, Ruggero Micheletto, Yoichi Kawakami, Maria Allegrini</i> . . . . .	321
10.1	Introduction . . . . .	321
10.2	Polarimetric Imaging . . . . .	322
10.2.1	The Jones Formalism . . . . .	325
10.3	Electromagnetic Field Diffracted by a SNOM Aperture . . . . .	327
10.4	Experimental Implementations . . . . .	333
10.4.1	Static Polarization SNOM . . . . .	333
10.4.2	Polarization-Modulation SNOM: Illumination Mode . . . . .	337
10.4.3	Polarization-Modulation SNOM: Collection Mode . . . . .	342
10.5	Applications of SNOM Polarimetry . . . . .	344
10.5.1	Polarization Responses of Photonic Waveguides . . . . .	345
10.5.2	Measuring Stress-Induced Birefringence . . . . .	348
10.5.3	Polarization Anisotropy in Mesoscale-Structured Materials . . . . .	349
10.5.4	Polarization Anisotropy in Polymers . . . . .	351
10.5.5	Polarization Anisotropy in Photoluminescence Emission . . . . .	354
10.6	Conclusions . . . . .	357
	References . . . . .	357

<b>11</b>	<b>Focused Ion Beam as a Scanning Probe: Methods and Applications</b>	
	<i>Vittoria Raffa, Piero Castrataro, Arianna Menciassi, Paolo Dario .</i>	361
11.1	Introduction . . . . .	361
11.2	Description of the System. . . . .	362
11.2.1	System Overview . . . . .	362
11.2.2	Liquid Metal Ion Source (LMIS) . . . . .	363
11.2.3	Ion Optics . . . . .	364
11.2.4	Dual Beam Systems . . . . .	365
11.3	FIB Processes . . . . .	367
11.3.1	Imaging . . . . .	367
11.3.2	Milling . . . . .	372
11.3.3	Gas-Assisted Etching . . . . .	376
11.3.4	Gas-Assisted Deposition . . . . .	377
11.3.5	Ion Beam Lithography . . . . .	379
11.4	Main Applications . . . . .	380
11.4.1	FIB as an Analytical Technique . . . . .	381
11.4.2	FIB in the Semiconductor Industry . . . . .	389
11.4.3	Micromachining . . . . .	401
11.5	Future Directions . . . . .	408
	References . . . . .	409
	<b>Subject Index</b> . . . . .	413

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